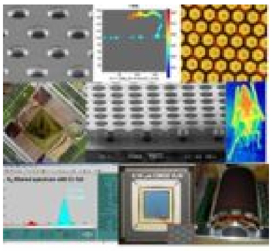
Micro Pattern Gas Detectors. Towards an R&D Collaboration.



Contribution ID: **46**

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# A test and certification of GEM foils produced by Tech-Etch

*Tuesday 11 September 2007 12:00 (20 minutes)*

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